

Digital Micromirror Devices

Presenter: Joey Groff

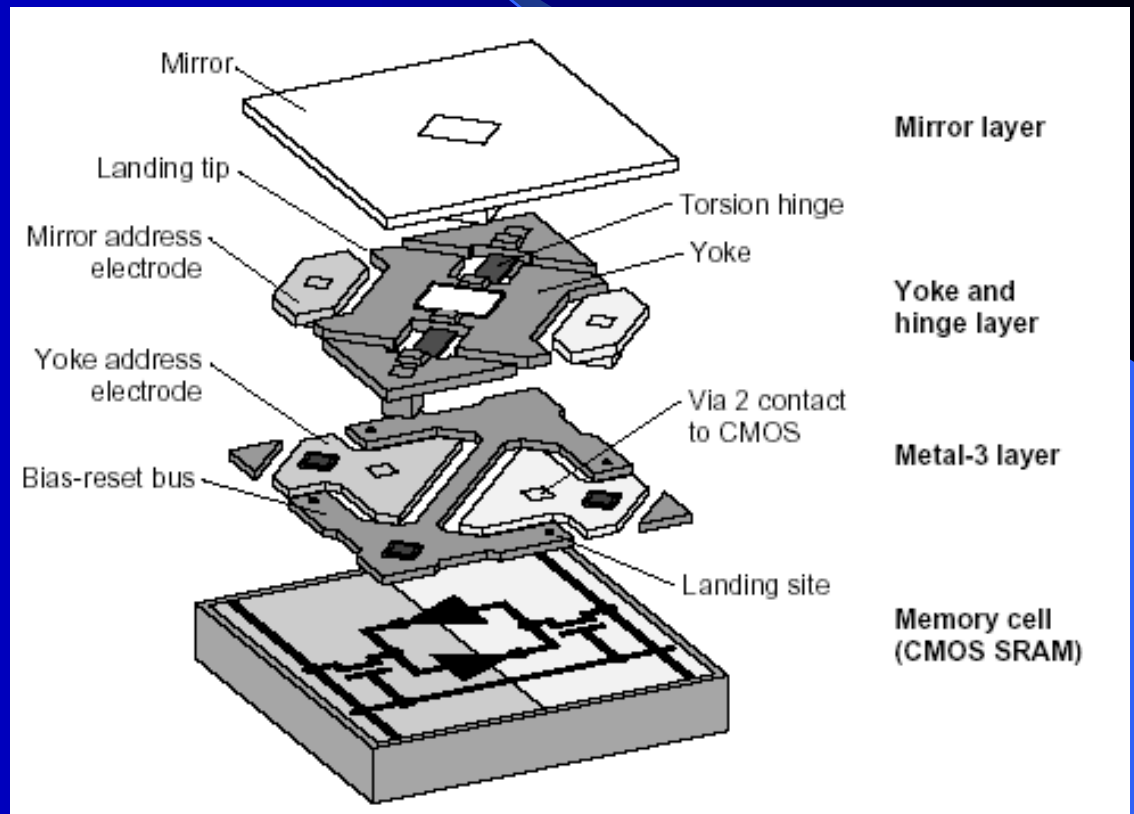
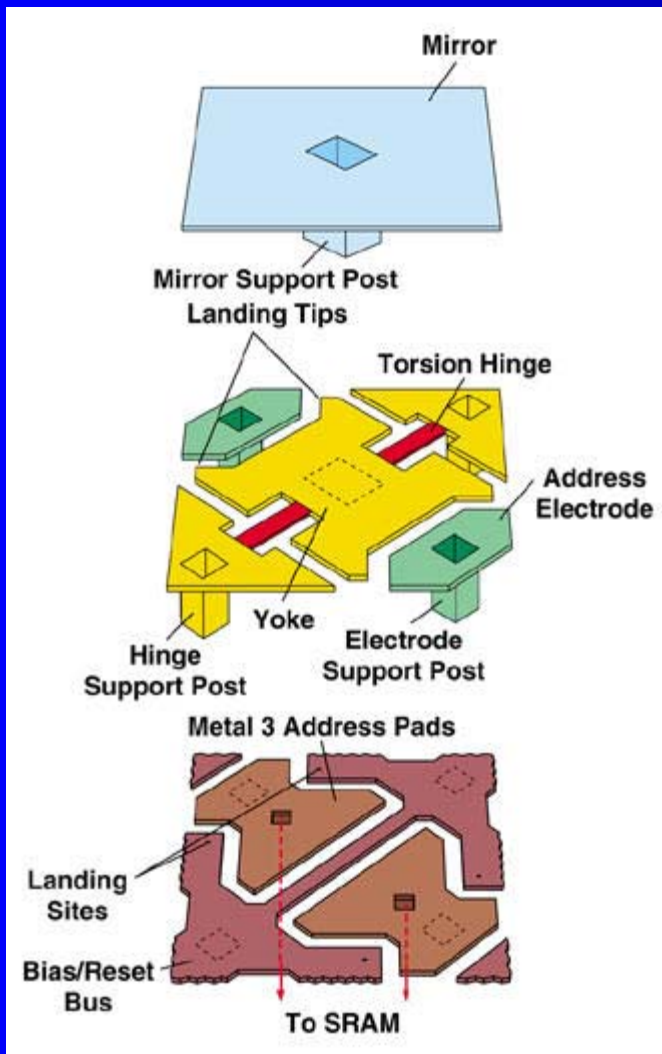
ECE 6450

November 18, 2002

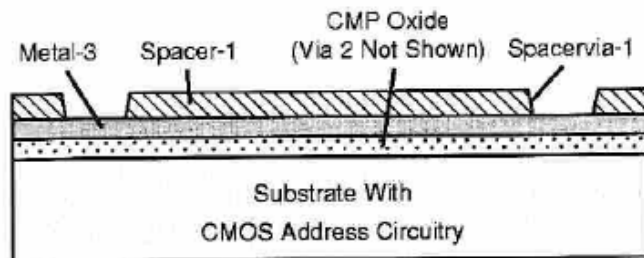
Digital Micromirror Devices

- Design
- Fabrication
- Specifications
- Specific Design Problems
- Applications
- Questions

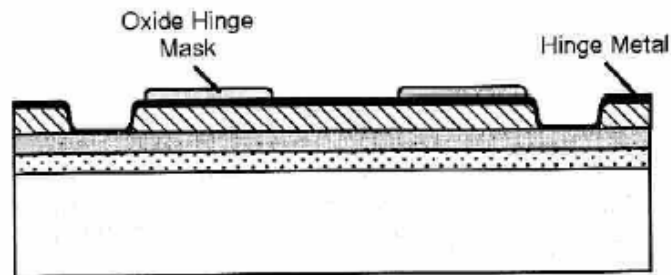
Structure



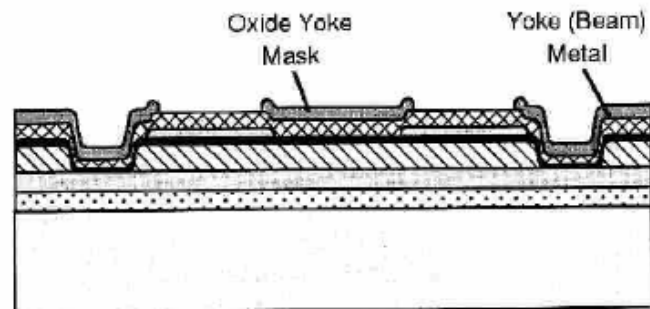
Fabrication Detail



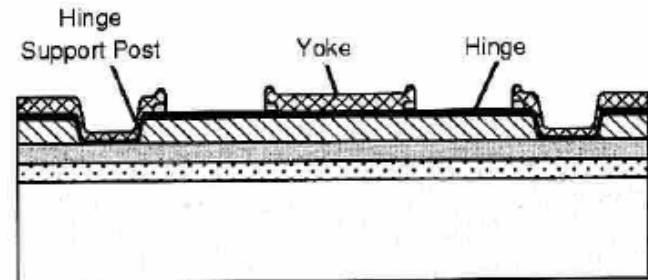
After Spacer-1 Patterning



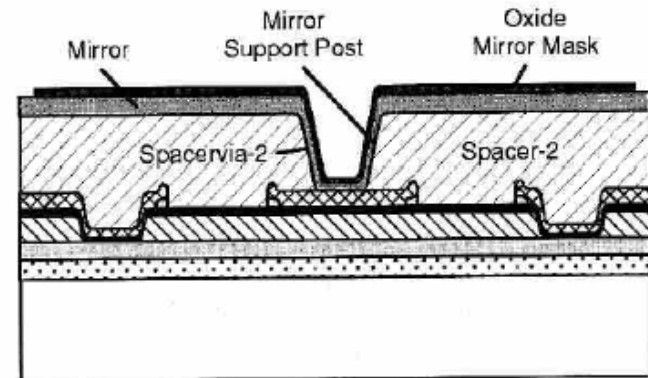
After Oxide Hinge Mask Patterning



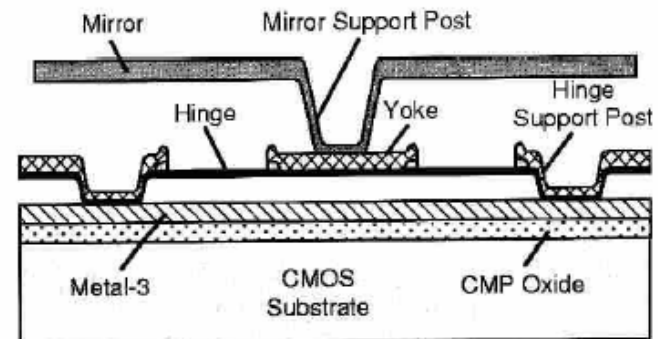
After Yoke Oxide Patterning



After Yoke/Hinge Etch and Oxide Strip

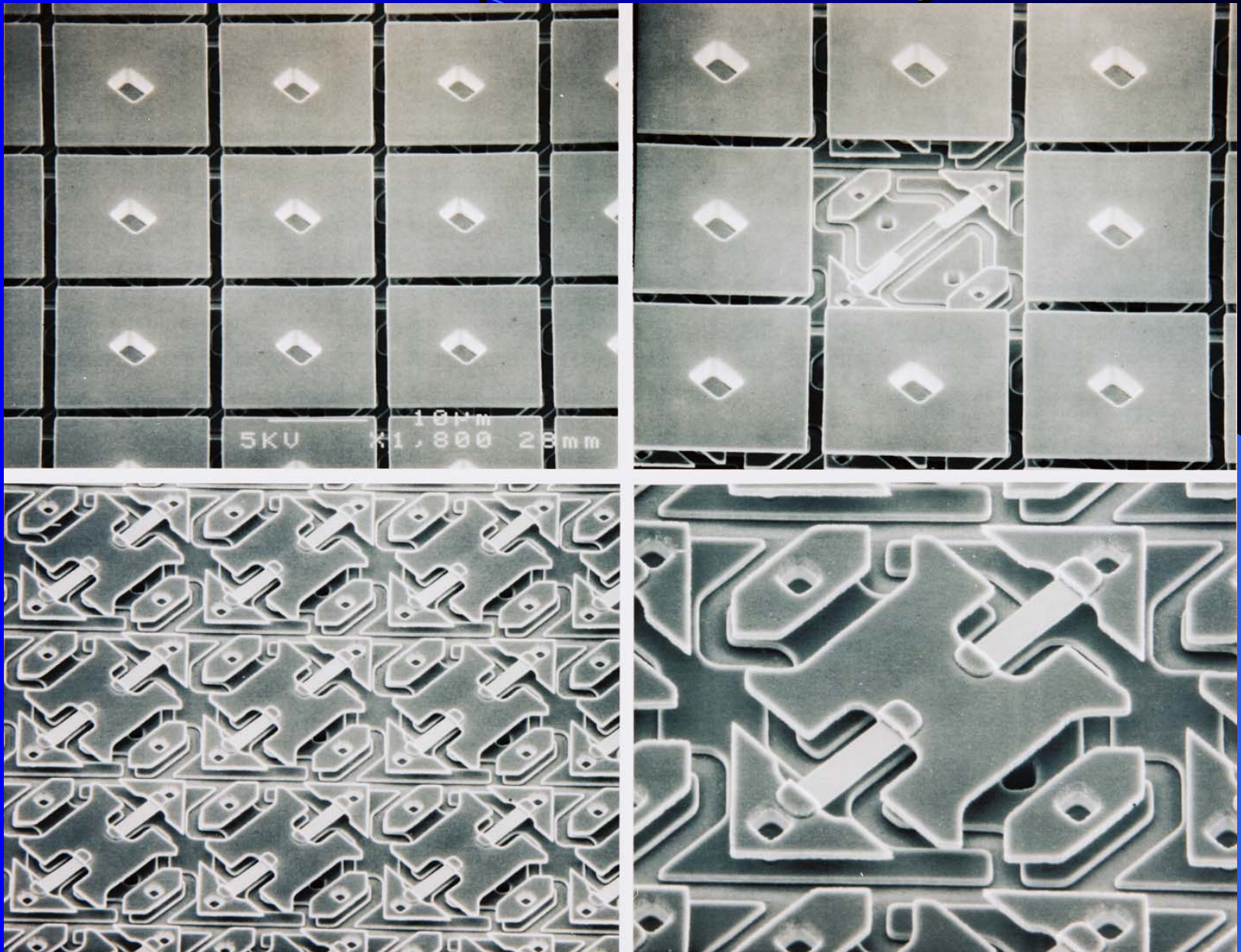


After Mirror Oxide Patterning



Completed Device

Completed Array



Specifications

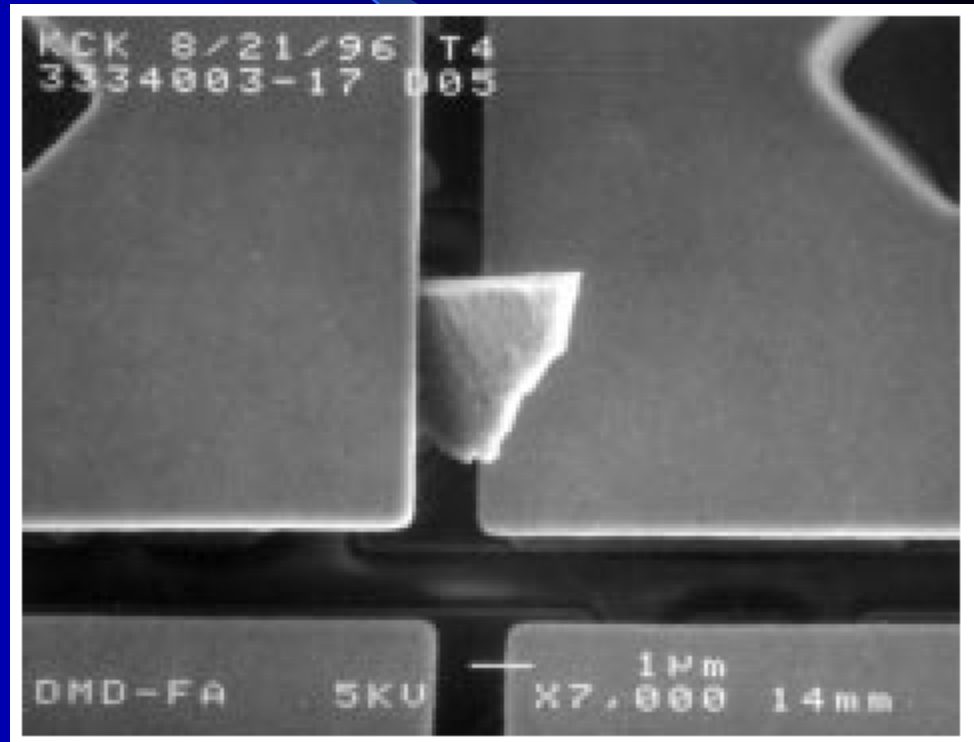
Mirror Size (TI's DLP)	16 μ m x 16 μ m
Mirrors per chip	0.5 – 1.2 million
Mirror Element	Aluminum
Lifetime Usage	450 billion contacts/part
CMOS Voltage	5V
CMOS Process Size	0.8 μ m
CMOS Design	Standard SRAM Cell

Design Considerations

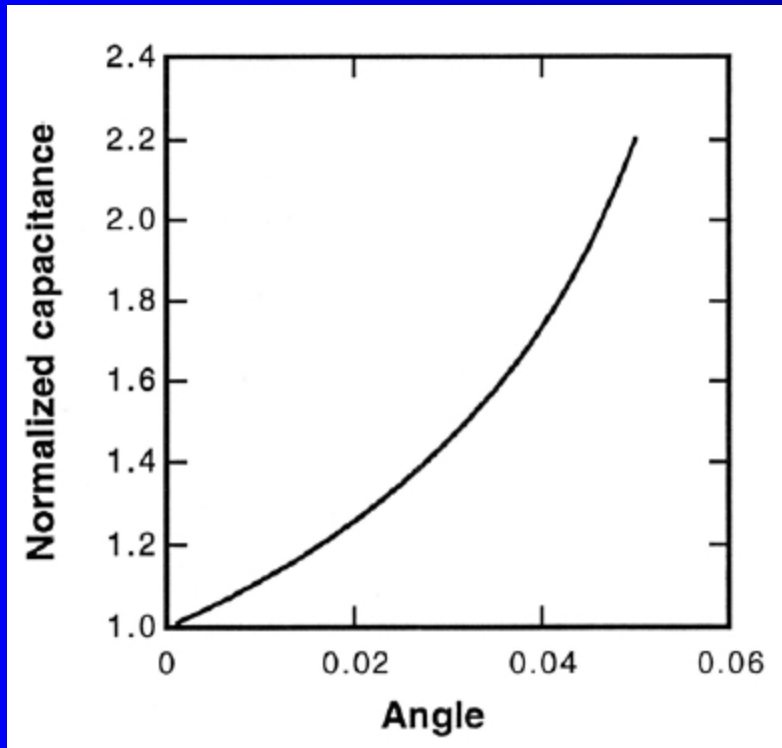
- Strict x, y, and z plane requirements
- Particle Control
- Physical contact during operation (tips)
- Optical lid and other packaging have tight design requirements
- Testing requires specialized equipment

Particle Control

- 1 μm gaps between mirrors
- 0.2 μm interlevel gaps during operation
- Specialized Cleaning Process Required



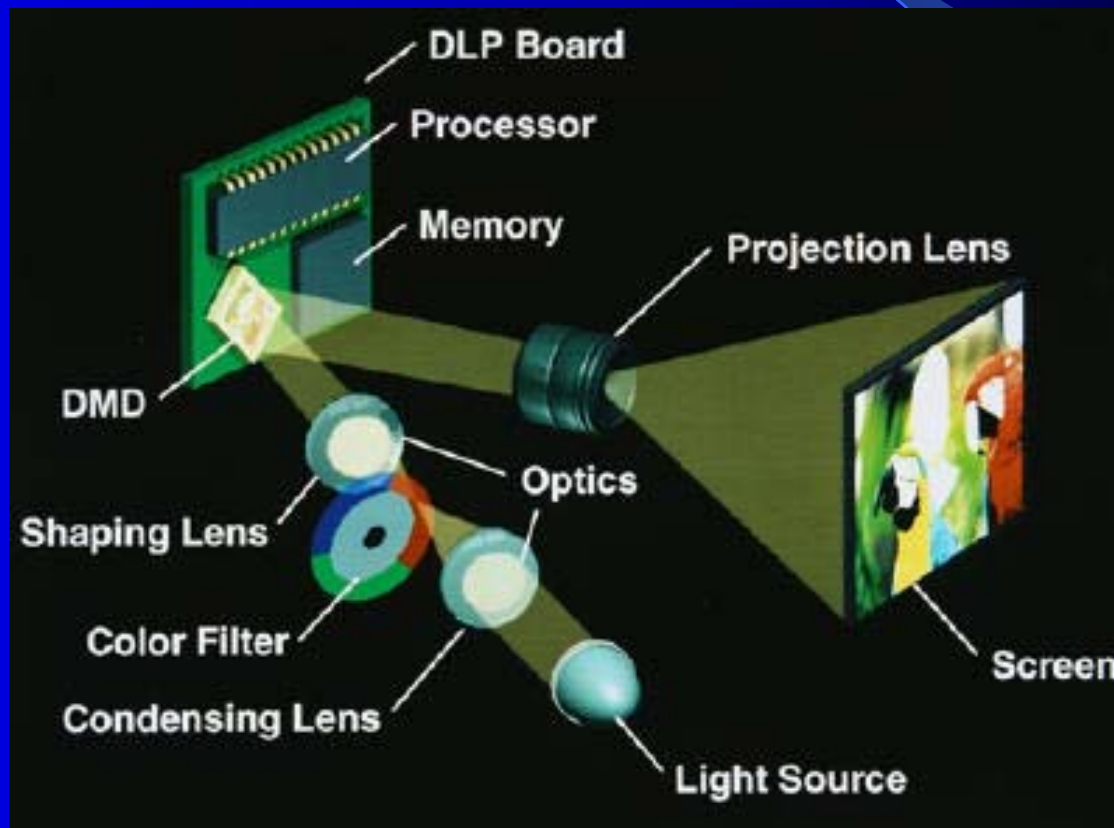
Control Equations



$$V_{PI} \propto \frac{1}{\sqrt{C}}$$

In most cases, there is only an on and off setting, so the CMOS understructure is designed for optimum voltage

Applications: Projection Display



Applications

- Variations on Projection Display:
2-chip and 3-chip
- Fiber Optic Switching: $N \times N$ matrices
 - reliable, fast
 - Lucent uses micromirrors in many fiberoptic applications
 - 20ns switching speed

Conclusions

- Once the chip is made, it's hard to break.
- DMD technology is the current leader in spectacular high definition TV and projector design.
- Further research into even tighter designs and better switching times can impact fiber optics further.

Questions?

